



Cohu<sup>®</sup>

Krypton<sup>™</sup>

# Inspection & Metrology Platform for Large Semiconductor Packages

## Next Generation Package Inspection Platform

- Saves IC devices manufacturers' inspection & metrology equipment 30% in capital expense, resulting in higher productivity.
- Increases throughput with innovative racing track technology and automatic yield recovery.
- Tray to Tape and reel and Tray to Tray process.
- Leaded, non-leaded packages QFN, QFP, BGA.
- 2 x 2 mm to 42.5 x 42.5 mm: up to 21,000 UPH including inspection.
- < 10 minutes automated conversion.
- Yield gain with Artificial Intelligence deep learning.
- Industry 4.0 AGV, OHT compatible Tray I/O.
- NV-Core<sup>™</sup> Inspection System provides 6-sided, 3D inspection & metrology with micro-scale defect detection.
- PAICe Digital Twin Platform<sup>™</sup> provides real-time equipment monitoring and data analytics for increased productivity.

# Krypton



## Package Inspection & Metrology Tray to Tray and Tray to Tape



**PAICe**  
INSPECTION™

### Up to 30% Higher Productivity

- Tray to Tape up to 21,000 UPH, Tray to Tray up to 16,000 UPH
- Featuring continuous-production race-track transfer technology with:
  - Direct sort of good and defective device for optimized throughput
  - Automatic second pass re-inspection for yield recovery
  - Micro-scale defect detection, 6-sided visible and infrared inspection, 3D Max vision system, and AI deep learning algorithms enabling pattern recognition and precise defect classification.
- Automation compatible solutions supporting factory automation and Industry 4.0.
- Semi-automated fast conversion, less than 10 minutes. Kit-less inspection stations.
- Footprint designed for floor space optimization less than 5 square meters.
- Extended scope of work to small devices in JEDEC tray down to 2 x 2 mm and larger devices up to 42.5 mm x 42.5 mm.

# NV-Core™

## Inspection System



- Full 6-sided single unit post testing inspection and metrology
- Visible and infrared inspection capability
- True 3D measurement at 6 µm repeatability
- Micro-scale defect detection down to 20 µm
- Full 1D or 2D ID unit-level traceability from tray input to tape & reel and tray output
- Vision assisted accurate device placement



# PAICe™

## Digital Twin Platform

- Real-time equipment monitoring and management
- Preventative maintenance
- Central recipe management
- Optimized yield and defect detection through real-time Artificial Intelligence inspection
- Knowledge database and unified reports



All specifications are subject to change without notification and are for reference only. For detailed performance specifications, please contact Cohu.

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[www.cohu.com/krypton](http://www.cohu.com/krypton)

Cohu, Inc.  
17087 Via Del Campo, San Diego, CA 92127-1711, USA  
Tel. +1-858-848-8000 | [info@cohu.com](mailto:info@cohu.com) | [www.cohu.com](http://www.cohu.com)  
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